

Sensors and Materials

Special Issue on

Advanced Nanofabrication Processes for Emerging Devices and Materials

Call for Papers:

Manufacturing is certainly a principal driver of sustainable and economic development of our society, as claimed in SDGs Goal 9. Recently, the progressive development of fabrication technologies has brought about the manufacturing revolution in various industrial fields. Here, micro- and nanotechnologies are fundamental and indispensable tools to spur the development.

This special issue will focus on the technical advancement of micro- and nano-fabrication processes in various types of emerging materials and devices, such as sensors, microactuators, energy harvestors, transmitter, and microTAS. Potential topics include the advancement of elemental technologies, such as thin-film deposition, lithography, etching, cleaning, and database-driven manufacturing.

Scope:

- Developments in processing of nanostructures
- Developments in processing of emerging devices
- Developments in nanomaterial characterizations
- Validation and reliability of nanoprocesses
- MEMS- and NEMS-related processes
- Novel devices and materials for sensors

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